



United States Patent [19]

Nakanishi et al.

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Date of Patent:

Aug. 1, 2000

[54]	SEMICONDUCTOR DEVICE HAVING
	MAGNETIC SHIELD LAYER
	CIRCUMSCRIBING THE DEVICE

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- [73] Assignees: Susumu Okamura; Takeshi Ikeda, both of Tokyo, Japan
- [21] Appl. No.:
- 09/171,455
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- § 371 Date:
- Oct. 19, 1998
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[30] Foreign Application Priority Data

- Apr. 24, 1996 [JP] Japan 8-127783
- [51] Int. Cl.⁷ H05K 1/00
- 257/676; 257/687; 257/700
 - 257/661, 676, 687, 700

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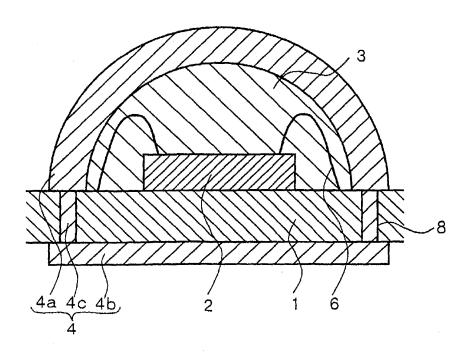
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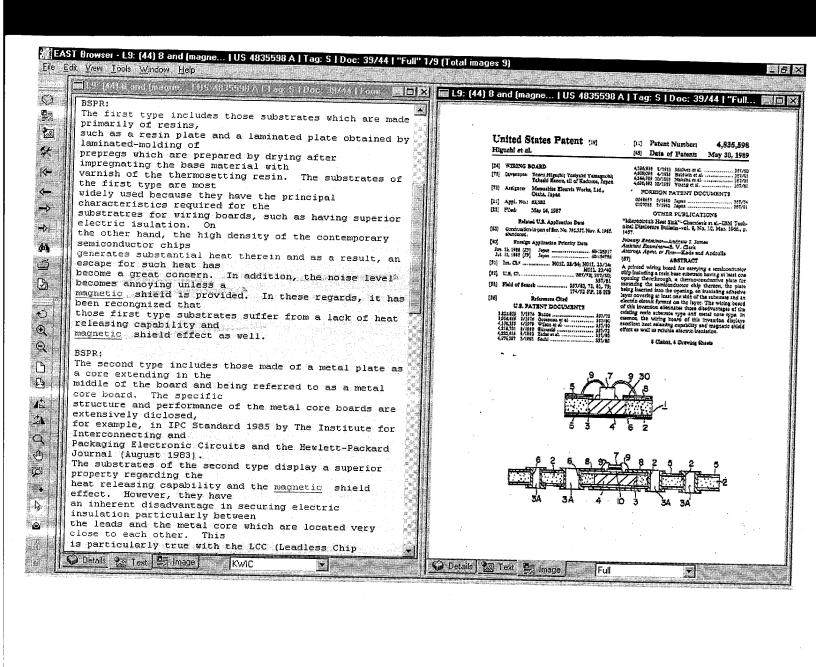
Primary Examiner-Fetsum Abraham Attorney, Agent, or Firm-Dellett and Walters

ABSTRACT [57]

It is the object to minimize a magnetic influence, on the outside, of a semiconductor chip which is formed on a substrate includes inductor conductors. A semiconductor chip 2 including inductor conductors is mounted on a substrate 1 and a plurality of through holes 8 are formed in the area on the outside of the mounting position. Shielding members 4 are formed on the chip mounting side and the opposite side of the substrate 1 and in the through holes 8 so as to cover the semiconductor chip 2 with the shielding members 4 from both sides of the substrate 1. Therefore, magnetic fluxes from a circuit formed on the semiconductor chip 2 do not leak out from the shielding members 4, but circulate inside the shielding members 4.

6 Claims, 3 Drawing Sheets

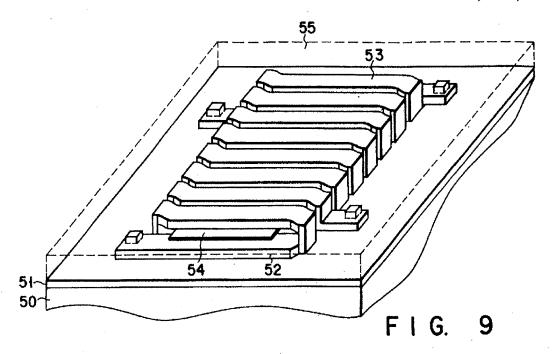


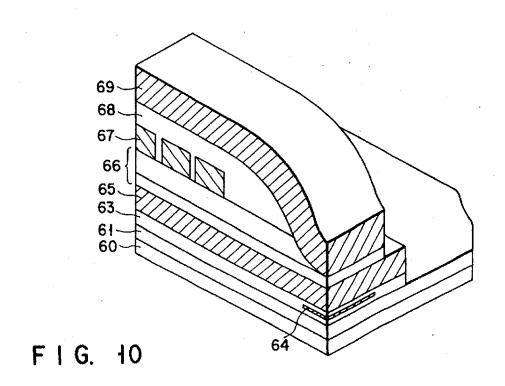


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5,738,931







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United States Patent [19]

Matsuyama et al.

[11] Patent Number: 5,851,681 [45] Date of Patent: Dec. 22, 1998

[54]	WIRING LAYERS,	STRUCTURE WITH METAL LAYERS AND POLYIMIDE AND FABRICATION PROCESS OF AYER WIRING BOARD
[75]	Inventors:	Haruhiko Matsuyama, Hiratsuka; Eiji Matsuzaki, Yokohama; Shozi Ikeda, Yokohama; Fumio Kataoka, Yokohama; Fusaji Shoji, Yokohama, all of Japan

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[21]	Appl.	No.:	212,766
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[22]	Filed:	Mar. 15, 1994
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[30]	ron	eign A	ppnear	non Friority Data
Mar. 15,	1993	[JP]	Japan	5-054318
(511 In	t. CL ⁶			G11B 5/40: C08G 69/20

[51]	Int. Cl.	G11B	5/40; C08G 69/26
[52]	U.S. CI.	428/473.5;	428/209; 428/458;
			174/258 528/353

[58]	Field of Search 428/209, 473.5,	
	428/615, 618, 458, 694 ML; 174/258	

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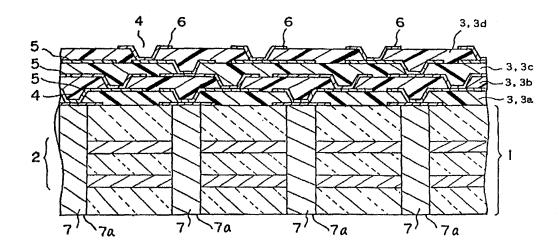
Shih, et al., 42nd Electric Compounds and Technology Conference, pp. 1002–1014, 1992. U.S. Ser. No. 7742044, filed Aug. 8, 1991. Advanced Organic Chemistry, 3rd Edition; Francis A. Carey and Richard J. Sundberg.

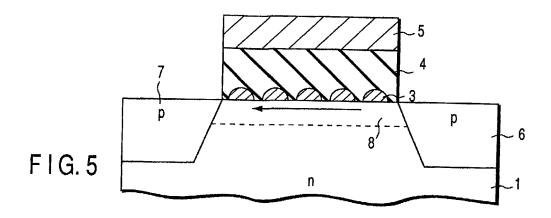
Primary Examiner—Cathy F. Lam Attorney, Agent, or Firm—Antonelli, Terry, Stout & Kraus,

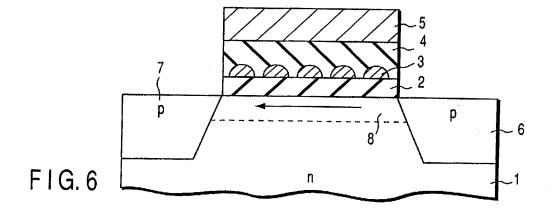
[57] ABSTRACT

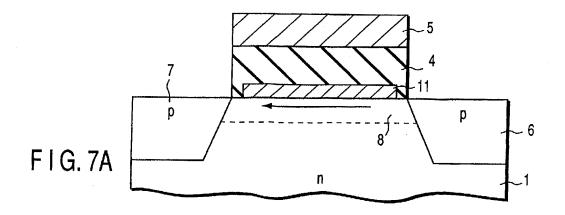
This invention relates to a wiring structure having metal wiring layers and polyimide layers. An object of this invention is to overcome problems caused by oxidation of a metal surface, such as an increase in the resistance of wiring and a reduction in insulation, by preventing a reaction between a metal of the wiring layers, such as copper, and carboxyl groups of polyamic acid which make up the polyimide layers. In the wiring structure according to the present invention, the polyimide layers have been formed by heating and curing a resin composition which comprises a polyimide precursor, an amine compound and an organic solvent.

14 Claims, 1 Drawing Sheet



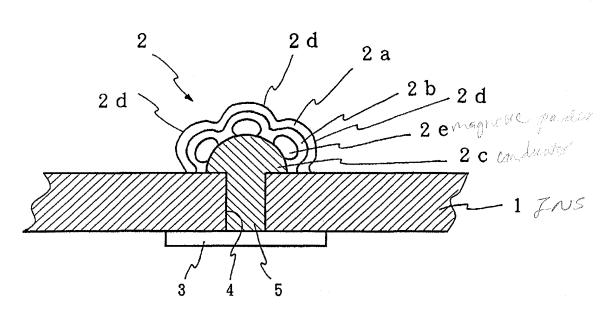






F I G. 3





F I G. 4

